



DFW

Attorney Docket: 081468-0305376
Client Reference: P-0362.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
VAN BILSEN et al.

Confirmation Number: 4408

Application No.: 10/665,404

Group Art Unit: 2878

Filed: September 22, 2003

Examiner: JOHN R. LEE

Title: ALIGNMENT SYSTEMS AND METHODS FOR LITHOGRAPHIC SYSTEMS

**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

REQUEST FOR INITIALED PTO-1449

Applicants gratefully acknowledge receipt of the Notice of Allowability dated March 13, 2007.

Upon review of the Examiner's initialed copy of the PTO-1449 form filed with the Information Disclosure Statement on February 10, 2004, Applicants find that the article listed was not initialed. A copy of the acknowledged PTO-1449 form attached to the Notice of Allowability and dated February 18, 2007 is attached hereto.

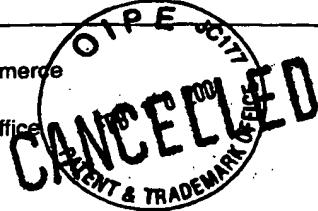
Also attached is a copy of the stamped Receipt, Information Disclosure Statement and PTO-1449 form filed on February 10, 2004. Applicants respectfully request that the Examiner acknowledge consideration of the article by signing, dating, and returning (to the undersigned) the enclosed copy of the PTO-1449 form.

Date: April 13, 2007

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FORM PTO-1449 (modified)
 To: U.S. Department of Commerce
 (PW FORM PAT-1449)
 Patent and Trademark Office



Atty.
 Dkt. No.

M#

Client Ref.

APR 13 2007

030537-0001 P-0362.010-US

**INFORMATION DISCLOSURE STATEMENT
 BY APPLICANT**

Date: February 10, 2004

Page **1** of **2**

Applicant: **VAN BILSEN et al.**

Appln. No.: **10/665,404**

Filing Date: **September 22, 2003**

Examiner: **Group Art Unit: 2881**

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
JL	AR	4,037,969	07/1977	FELDMAN et al.			
	BR	4,236,805	04/1982	FELDMAN et al.			
	CR	4,251,160	02/1981	BOUWHUIS et al.			
	DR	4,355,892	10/1982	MAYER et al.			
	ER	4,398,824	08/1983	FELDMAN et al.			
	FR	4,514,858	04/1985	NOVAK			
	GR	4,540,277	09/1985	MAYER et al.			
	HR	4,614,432	09/1986	KUNIYOSHI et al.			
	IR	4,690,529	09/1987	SUGIYAMA et al.			
	JR	4,710,026	12/1987	MAGOME et al.			
	KR	4,748,333	05/1988	MIZUTANI et al.			
	LR	4,778,275	10/1988	VAN DEN BRINK et al.			
	MR	4,814,829	03/1989	KOSUGI et al.			
	NR	4,828,392	05/1989	NOMURA et al.			
	OR	4,857,744	08/1989	KATAOKA et al.			
	PR	4,861,162	08/1989	INA			
	QR	4,870,452	09/1989	TANIMOTO et al.			
	RR	4,952,970	08/1990	SUZUKI et al.			
	SR	5,100,237	03/1992	WITTEKOEK et al.			
↓	TR	5,114,236	05/1992	MATSUGU et al.			
	UR	5,118,953	06/1992	OTA et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
JL	VR	11-329914	11/1999	Japan	SAKO TAKASHI	X			X
WR									
XR									
YR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

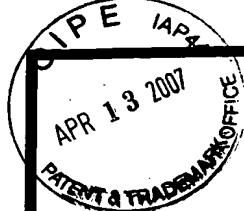
ZR	Markle, D. A., "Submicron 1:1 Optical Lithography", Semi-conductor International, pp. 173-142, May 1986.	X
AAR		
BBR		
CCR		

Examiner **/John Lee/ (02/18/2007)**

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

PAT-1449 12/98

**RECEIPT FROM PTO FOR INDICATED ITEMS**

(Do NOT Use for New or Continuing Applications of Any Kind)
Use 2 postcards for all New Applications (including cont/Div/CIP)
Use this sheet when filing CPA or RCE

Appln. No: 10/665,404	Atty: Henry J. Daley/R. Parra
First Inventor: FRANK VAN BILSEN	Date: February 10, 2004
Title: ALIGNMENT SYSTEMS AND METHODS FOR LITHOGRAPHIC SYSTEMS	Attorney Docket No: 081468-0305376

ENCLOSED:

Response to Missing Part.

Declaration 5 of pages

Assignment Request for Recordation

IDS Letter

Cited Appln(s)

PTO-1449

Cited/Listed Documents

Fee Transmittal

\$ 5,248.00 Total Fee Charged to Deposit Account

CURRENT DUE DATE: February 12, 2004



Docket Number: 081468-0305376
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PATENT APPLICATION

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In Re the Application of

VAN BILSEN et al.

Group Art Unit: 2881

Application No.: 10/665,404

Examiner:

Filed: September 22, 2003

Confirmation No.: 4408

For: ALIGNMENT SYSTEMS AND METHODS FOR LITHOGRAPHIC SYSTEMS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
 P. O. Box 1450
 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

The undersigned respectfully notes that copies of U.S. references are not required in applications filed after June 30, 2003

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

This application is one of a series of related applications, identified in the attached Appendix, which are directed to related technical subject matter. The identification of those U.S. Patent Applications is not to be construed as a waiver of secrecy as to those applications now or upon issuance of the present application as a patent. The Examiner is respectfully requested to consider the cited applications and the art cited therein during examination.

Respectfully Submitted,

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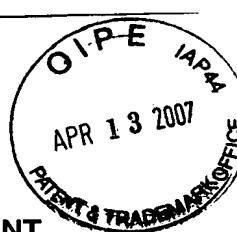
APPENDIX

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	Navarro y Koren et al.	10/665,364	September 22, 2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: Papers as filed including any Preliminary Amendment
	Den Boef et al.	10/665720	September 22, 2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: Papers as filed including any Preliminary Amendment
	Van Haren et al.	10/665360	September 22, 2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: Papers as filed including any Preliminary Amendment

The Examiner's initials indicates he/she has considered the cited application relative to the subject application.

DO NOT PRINT the above information on the patent which results from the subject application.

Best Available Copy



0305376

P-0362.010-US

Applicant: VAN BILSEN et al.

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Date: February 10, 2004

Page 2 of 2

er: Group Art Unit: 2881

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	5,144,363	09/1992	WITTEKOEK et al.			
	BR	5,151,754	09/1992	ISHIBASHI et al.			
	CR	5,160,849	11/1992	OTA et al.			
	DR	5,243,195	09/1993	NISHI			
	ER	5,347,356	09/1994	OTA et al.			
	FR	5,418,613	05/1995	MATSUTANI			
	GR	5,477,057	12/1995	ANGELEY et al.			
	HR	5,488,230	01/1996	MIZUTANI et al.			
	IR	5,489,986	02/1996	MAGOME et al.			
	JR	5,543,921	08/1996	UZAWA et al.			
	KR	5,559,601	09/1996	GALLATIN et al.			
	LR	5,596,204	01/1997	IRIE et al.			
	MR	5,801,390	09/1998	SHIRAI SHI			
	NR	5,808,910	09/1998	IRIE et al.			
	OR	5,920,376	07/1999	BRUCKSTEIN et al.			
	PR	5,920,378	07/1999	MURAKAMI et al.			
	QR	6,034,378	03/2000	SHIRAI SHI			
	RR	6,133,641	10/2000	HAMADA et al.			
	SR	6,233,494 B1	05/2001	AOYAGI			
	TR	6,242,754 B1	06/2001	SHIRAI SHI et al.			
	UR	6,297,876 B1	10/2001	BORNEBROEK			

FOREIGN PATENT DOCUMENTS

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

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